

Title (en)  
MICROMECHANICAL STRUCTURE

Title (de)  
MIKROMECHANISCHE STRUKTUR

Title (fr)  
STRUCTURE MICROMÉCANIQUE

Publication  
**EP 2435786 A1 20120404 (DE)**

Application  
**EP 10702076 A 20100120**

Priority  
• EP 2010050634 W 20100120  
• DE 102009026476 A 20090526

Abstract (en)  
[origin: WO2010136222A1] What is proposed is a micromechanical structure, more particularly an acceleration sensor, comprising a substrate, a seismic mass that is movable relative to the substrate, and at least one anchoring element that is fixedly connected to the substrate, wherein the seismic mass is fixed to the substrate by means of the anchoring element, and wherein at least one spring element is arranged between the seismic mass and the anchoring element, and wherein, furthermore, the anchoring element has at least one stop element for interaction with at least one counter-stop element of the seismic mass.

IPC 8 full level  
**G01C 19/56** (2012.01); **G01P 15/125** (2006.01)

CPC (source: EP US)  
**G01P 15/125** (2013.01 - EP US); **G01P 2015/0814** (2013.01 - EP US)

Citation (search report)  
See references of WO 2010136222A1

Citation (examination)  
DE 10051973 A1 20020502 - BOSCH GMBH ROBERT [DE], et al

Designated contracting state (EPC)  
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO SE SI SK SM TR

DOCDB simple family (publication)  
**DE 102009026476 A1 20101202**; CN 102449488 A 20120509; EP 2435786 A1 20120404; JP 2012528305 A 20121112;  
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**DE 102009026476 A 20090526**; CN 201080022900 A 20100120; EP 10702076 A 20100120; EP 2010050634 W 20100120;  
JP 2012512261 A 20100120; TW 99116450 A 20100524; US 201013259392 A 20100120